

1763
Jhw



Attorney's Docket No.: 005794 ALRT/ETCH/CONE/
Confirmation No.: 3777

Patent

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:)	
)	
Mark N. Kawaguchi, et al.)	
)	Examiner: Olsen, Allan W.
Application No: 09/978,121)	
)	Art Unit: 1763
Filed: October 15, 2001)	
)	
For: A METHOD OF PHOTORESIST)	
REMOVAL IN THE PRESENCE OF)	
A DIELECTRIC LAYER HAVING)	
A LOW K-VALUE)	
_____)	

Mail Stop: Amendment
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action dated May 5, 2004, Applicant respectfully requests that the above-identified application be amended as follows and that the following remarks be considered:

FIRST-CLASS CERTIFICATE OF MAILING

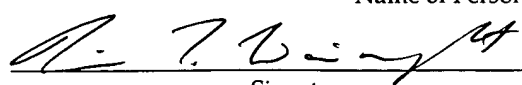
I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail with sufficient postage in an envelope addressed to Mail Stop: Amendment, Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450, on:

September 7, 2004

Date of Deposit

Tina Wainright

Name of Person Mailing Correspondence



Signature

September 7, 2004

Date

Inventor(s): Mark N. Kawaguchi, et al.
Application No.: 09/978,121

Examiner: Olsen, Allan W.
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